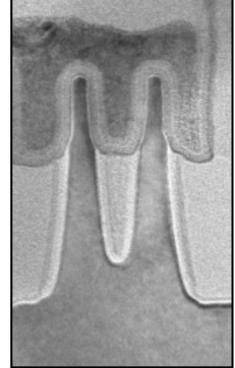
Special Topics on Basic EECS I Design Technology Co-Optimization Lecture 5

Sung-Min Hong (smhong@gist.ac.kr)
Semiconductor Device Simulation Laboratory
Department of Electrical Engineering and Computer Science
Gwangju Institute of Science and Technology (GIST)

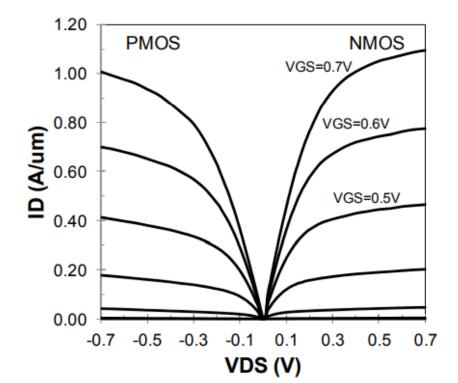
L5

Intel 14 nm @ IEDM 2014

- 16 years later,
 - -First of all, it is not a planar MOSFET but a FinFET.
 - -Fin pitch is 42 nm. Contacted gate pitch is 70 nm.
 - -Gate length is 20 nm. SRAM: 0.0588 μm²



Transistor
IV curves
(Intel)
GIST Lecture



Transistor fin image (Intel)

FinFET

- A tall fin
 - "Tri-gate" by Intel
 - It's like a double-gate.
- Then, why double-gate?
 - -Better gate controllability (We all know it.)

Spacer Fin surrounded by S/D the gate oxide S/D **GIST** Lecture

3D structure of a FinFET transistor (Synopsys)

Lesson from "VLSI Devices" (1)

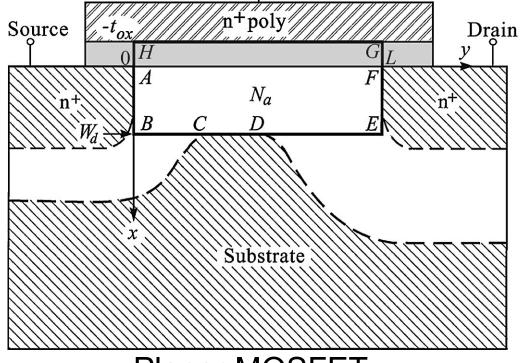
- In the subthreshold regime, we may solve
 - The Poisson equation without inversion charges

$$\frac{\partial^2 \phi}{\partial x^2} + \frac{\partial^2 \phi}{\partial y^2} = -\frac{qp(x,y)}{\epsilon_{si}} + \frac{qN_a}{\epsilon_{si}}$$

- Hole density is a nonlinear function of $\phi(x,y)$.
- It can be neglected

in the depletion region.
$$\frac{\partial^2 \phi}{\partial x^2} + \frac{\partial^2 \phi}{\partial y^2} = \frac{qN_a}{\epsilon_{si}}$$

For your interest, watch the video, [Eng][VLSIDevi ces2025] L16, L17, and L18



Gate

Planar MOSFET (Prof. Taur's book)

Lesson from "VLSI Devices" (2)

- Boundary conditions by terminal voltages
 - Try the following function:

$$\phi(x,y) = v(x,y) + u_L(x,y) + u_R(x,y) + u_B(x,y)$$

Poisson equation with upper b.c. (Long-channel)

Laplace equation to match left b.c.

Laplace equation to match right b.c.

-Then,

$$\frac{\partial^2 u_R}{\partial x^2} + \frac{\partial^2 u_R}{\partial y^2} = 0$$

For your interest, watch the video, [Eng][VLSIDevi ces2025] L16, L17, and L18

Laplace equation to match bottom b.c.

Lesson from "VLSI Devices" (3)

- Solution of Laplace equation
 - -Separation of variables

$$u_R(x,y) = X(x)Y(y)$$

-When
$$\frac{d^2X}{dx^2} = -\frac{1}{\lambda^2}X$$
 and $\frac{d^2Y}{dy^2} = \frac{1}{\lambda^2}Y$,



$$\frac{d^2X}{dx^2}Y + X\frac{d^2Y}{dy^2} = 0$$

For your interest, watch the video, [Eng][VLSIDevices2025] L16, L17, and L18

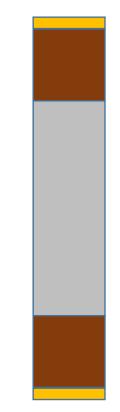
Exponential functions

Sinusoidal functions

- The vertical variation and the lateral variation are coupled.

Compare two structures.

- Calculate λ for two structures
 - -1) Double-gate (from $x = -\frac{t_{si}}{2}$ to $x = \frac{t_{si}}{2}$)
 - Top- and bottom-gates
 - -Symmetric about x = 0
 - -2) (Almost) single-gate (from x = 0 to $x = t_{si}$)
 - Only top-gate
 - Vanishing electric field at x = 0





Boundary condition

- Continuity of displacement @ Si/SiO₂ interface
 - -Assume that u_R is a homogeneous solution induced by the drain voltage.
 - -1) Double-gate

The engate
$$\left. \begin{array}{c|c} \left. \frac{\partial u_R}{\partial x} \right|_{x = \frac{t_{Si}}{2}, y} = -\epsilon_{ox} \frac{u_R \left(x = \frac{t_{Si}}{2}, y \right)}{t_{ox}} \right. \end{array} \right. \text{ Vertical components only engate }$$

-2) Single-gate

$$\left. \epsilon_{si} \frac{\partial u_R}{\partial x} \right|_{x=t_{si}, y} = -\epsilon_{ox} \frac{u_R(x=t_{si}, y)}{t_{ox}}$$

Boundary condition for X(x)

- Recall $u_R(x,y) = X(x)Y(y)$.
 - -1) Double-gate

$$\left. \epsilon_{si} \frac{dX}{dx} \right|_{x = \frac{t_{si}}{2}, y} = -\epsilon_{ox} \frac{X\left(x = \frac{t_{si}}{2}\right)Y}{t_{ox}}$$

-2) Single-gate

-2) Single-gate
$$\epsilon_{si} \frac{dX}{dx} \bigg|_{x=t_{si},y} = -\epsilon_{ox} \frac{X(x=t_{si})Y}{t_{ox}}$$
 -In both cases, $\frac{dX}{dx} = -\frac{\epsilon_{ox}}{\epsilon_{xi}t_{ox}} X$ at Si/SiO₂ interface.

Double-gate

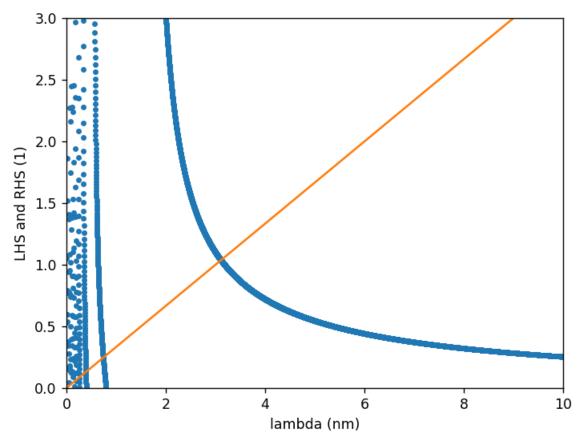
• Due to symmetry, $X(x) = \cos \frac{x}{\lambda}$. (Sine function is not possible.)

$$-\epsilon_{si} \frac{1}{\lambda} \sin \frac{t_{si}}{2\lambda} = -\epsilon_{ox} \frac{\cos \frac{c_{si}}{2\lambda}}{t_{ox}}$$
$$\tan \frac{t_{si}}{2\lambda} = \frac{\epsilon_{ox}}{\epsilon_{si} t_{ox}} \lambda$$

-An example)

 t_{si} = 5 nm and t_{ox} = 1 nm ϵ_{si} is three times ϵ_{ox} .

 \rightarrow Largest λ is 3.111 nm.



Single-gate

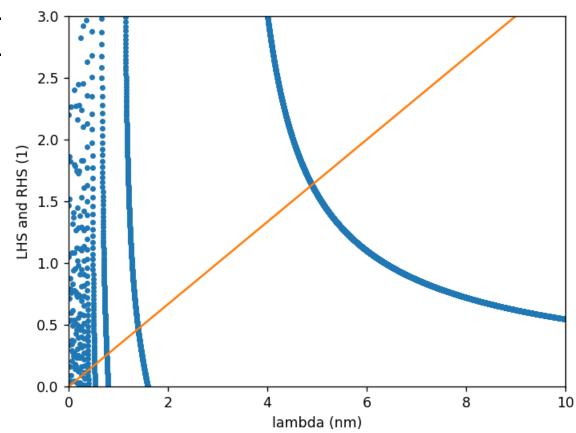
• Again, due to the boundary condition at x = 0, $X(x) = \cos \frac{x}{x}$. (Sine function is not possible.)

$$-\epsilon_{si} \frac{1}{\lambda} \sin \frac{t_{si}}{1\lambda} = -\epsilon_{ox} \frac{\cos \frac{t_{si}}{1\lambda}}{t_{ox}}$$
$$\tan \frac{t_{si}}{1\lambda} = \frac{\epsilon_{ox}}{\epsilon_{si} t_{ox}} \lambda$$

-An example)

 t_{si} = 5 nm and t_{ox} = 1 nm ϵ_{si} is three times ϵ_{ox} .

 \rightarrow Largest λ is 4.897 nm.



Approximate expressions

Two structures share the same expression.

$$\tan \frac{t_{si}}{N\lambda} = \frac{\epsilon_{ox}}{\epsilon_{si}t_{ox}}\lambda$$

 Although not perfect (as shown in our example), it is frequently approximated as

$$\frac{t_{si}}{N\lambda} = \frac{\epsilon_{ox}}{\epsilon_{si}t_{ox}}\lambda$$

$$\lambda = \sqrt{\frac{\epsilon_{si}}{N\epsilon_{ox}}t_{si}t_{ox}}$$

-This expression yields 2.7 nm (DG) and 3.9 nm (SG), respectively.

Thank you!